

**AMENDMENTS TO THE CLAIMS**

Please amend the claims as follows.

1. (Currently Amended) A method for manufacturing an optical device, comprising:
  - coating a substrate with a resin thin layer, wherein temperature of the resin thin layer is controlled lower than a polymerization reaction starting temperature thereof and the resin is not substantially polymerized;
  - heating the resin thin layer to a temperature higher than polymerization reaction starting temperature and glass-transition temperature but lower than a thermal decomposition starting temperature of the resin so that the resin thin layer is polymerized on the substrate to form a resin thin film thereon;
  - pressing a stamp having an inverted micro-asperity pattern against the resin thin film such that a micro-asperity pattern is formed on a surface of the resin thin film, wherein the stamp is pressed against the resin thin film a plurality of times;
  - cooling the resin thin film to a temperature lower than the glass-transition temperature;
  - [[and]]
  - separating the stamp from the resin thin film; and
  - baking an alignment film on the resin thin film at a temperature lower than the glass-transition temperature to prevent the micro-asperity pattern formed on the surface of the resin thin film from losing shape.
2. - 3. (Cancelled)
4. (Original) The method according to claim 1, wherein the micro-asperity pattern is formed on the surface of the resin thin film in an inert gas atmosphere.
5. (Original) The method according to claim 1, wherein the micro-asperity pattern is formed on the surface of the resin thin film in a chamber, and pressure inside the chamber is maintained lower than atmospheric pressure.
6. - 31. (Cancelled)